



Docket No.: 1076.1063

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Yuuichi TACHINO et al.

Serial No. 09/775,653

Group Art Unit: 1763

Confirmation No. 9294

Filed: February 5, 2001

Examiner: Anna M. Crowell

For: PLASMA ETCHING METHOD AND APPARATUS

AMENDMENT AND RESPONSE

Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

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Sir:

This is in response to the Office Action mailed October 16, 2003, and having a period for response set to expire on January 16, 2003. A petition and fee for a two-month Extension of Time is enclosed, thereby extending the response period to March 16, 2004.

The following amendments and remarks are respectfully submitted. Reconsideration of the claims is respectfully requested.

03/17/2004 SDENB0B1 00000135 09775653

01 FC:1201

172.00 OP

03/17/2004 SDENB0B1 00000135 09775653

02 FC:1252

420.00 OP

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